

Scanning Probe Microscope/Atomic Force Microscope

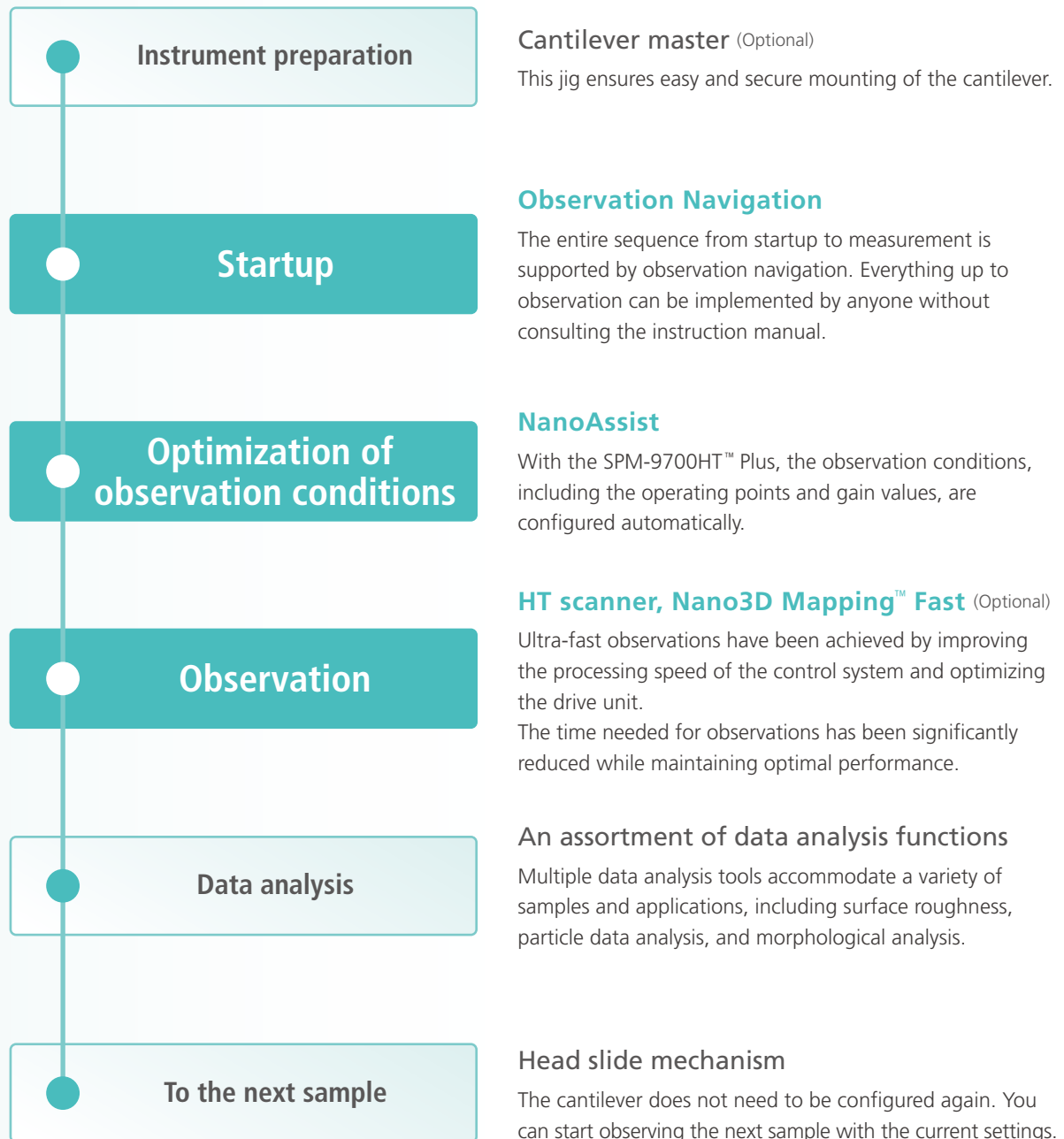
SPM-9700HT Plus



Observations Independent of the Operator

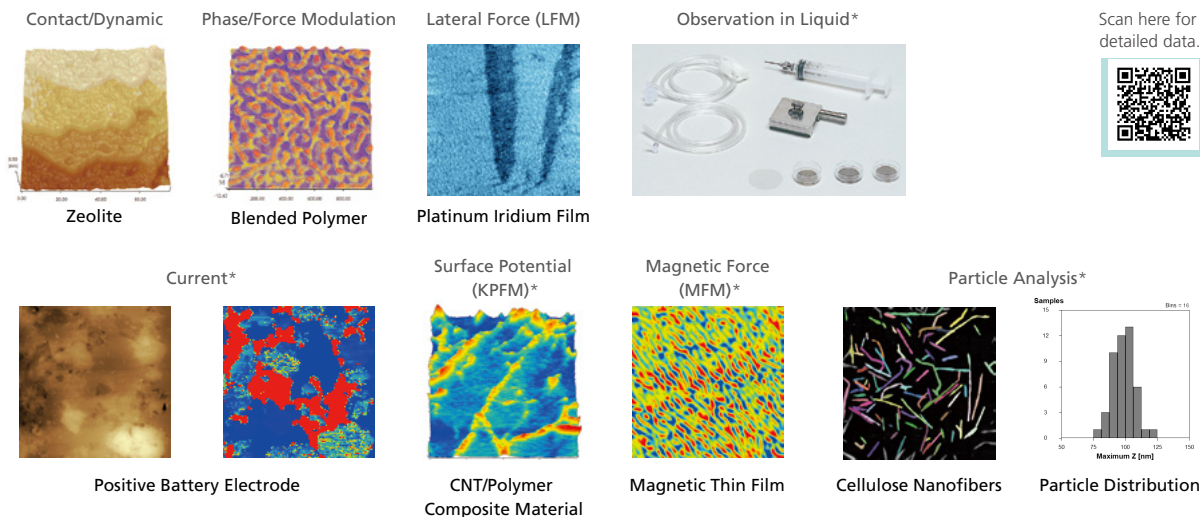


The system and software are equipped with Analytical Intelligence, our user support technology that provides maximum support for the overall workflow, from data acquisition to analysis.



- Automated support functions utilizing digital technology, such as M2M, IoT, and Artificial Intelligence (AI), that enable higher productivity and maximum reliability.
- Allows a system to monitor and diagnose itself, handle any issues during data acquisition without user input, and automatically behave as if it were operated by an expert.
- Supports the acquisition of high quality, reproducible data regardless of an operator's skill level for both routine and demanding applications.

Application Mode Accommodates an Assortment of Samples



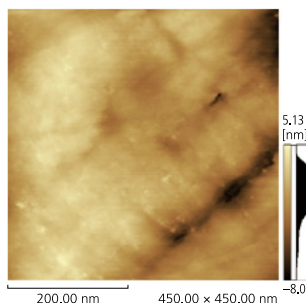
* Option

NEW Nano3D Mapping Fast (Optional)

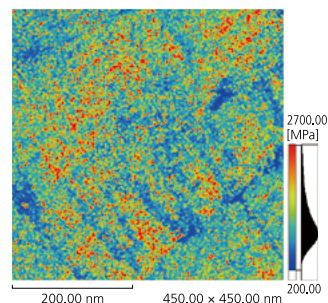
The time required for physical property mapping has been significantly reduced compared to the previous machine (SPM-9700HT). The shorter mapping time enables stable physical property evaluation.

High-Density Polyethylene

Observation time
Approx.
27 min



Surface Shape

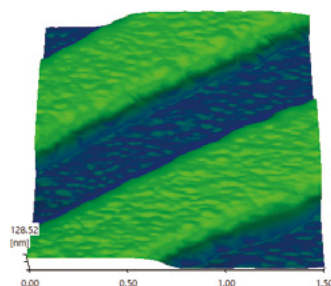


Elastic Modulus Map

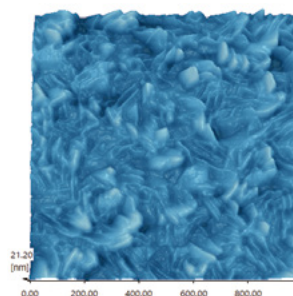
NEW NanoAssist Optimizes Observation Conditions

Only the observation range needs to be set. Other observation conditions are set automatically.

Shape Images Obtained with NanoAssist



Diffraction Grating



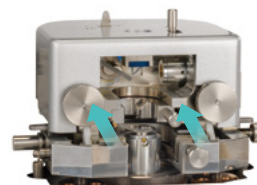
Vapor-Deposited Nb Coating

High-Throughput Observations

Head Slide Mechanism

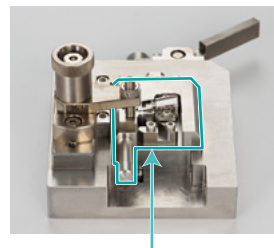
The design allows space around the sample, while maintaining a high level of rigidity.

- Samples can be replaced without removing the cantilever holder.
- Samples can be accessed even during SPM observations.
- Samples are approached automatically, regardless of the sample thickness.



Cantilever Master Cantilever Mounting Jig (Optional)

Even small cantilevers can be attached with ease.



Cantilever holder

Installation Specifications

• Installation Environment

The following conditions are preferable for the installation environment.

Temperature 23 °C ± 5 °C

Humidity 60 % max. (no condensation)

• Power Supply

The power supply listed is required for operating this instrument.

SPM-9700HT Plus

Single-phase 100 to 120 V, 50/60 Hz, 15 A, 2 circuits

Grounding Type D grounding (maximum resistance 100 Ω)

- The above-mentioned is the power supply for the basic SPM-9700HT Plus specifications. This will change depending on the optional configuration. For details, refer to the specifications.

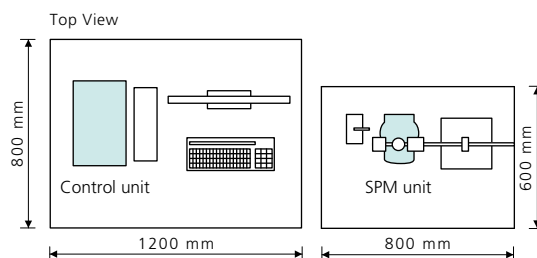
• Size and Weight

SPM unit: W180 × D255 × H260 mm, 5.5 kg

Control unit: W250 × D420 × H454 mm, 18.5 kg

• Laser product classification

Class 1 Laser product (IEC 60825-1:2014)



- This figure is one example of a configuration.
- The sizes of the OA table and desk-type air-spring vibration damper are for reference.

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